Red, Green and Blue Silicate Phosphor Thin Films by Pulsed Laser Deposition

X. W. Sun and H. S. Kwok Center for Display Research Department of Electrical and Electronic Engineering The Hong Kong University of Science and Technology Clear Water Bay, Kowloon, Hong Kong

Abstract

Three kinds of silicate phosphor thin films, emitting in the red-green-blue (RGB) primary colors, were fabricated by pulsed laser deposition: manganese and lead doped calcium silicate (CaSiO₃:MnPb) for red color, manganese doped zinc silicate (Zn₂SiO₄:Mn) for green color, and cerium doped yttrium silicate (Y_2SiO_5 :Ce) for blue color. A good correlation was found between photoluminescence intensity and film crystallinity and surface morphology.

Introduction

Phosphors are widely used in emissive displays. However, all currently used phosphors still need considerable improvement such as in lower current saturation, high efficiency, and better chromaticity [1]. Oxide phosphor (including silicate phosphor) is more chemically stable than sulfide phosphors under high Coulomb loading. As a matter of fact, silicate phosphors such as Zn_2SiO_4 :Mn have been used in CRTs. Electroluminescence (EL) device have also been made from these same silicate [2]. In all the display applications, thin film phosphor is preferred over powder phosphors due to its high contrast ratio, high ambient visibility, high image resolution and good heat resistance [3].

Pulsed laser deposition (PLD) technique, which has been quite successful in depositing complex superconducting oxide thin films, provides a unique process for stoichiometric evaporation of target materials [4]. Doped silicate phosphor is a complex compound system, which generally consisted of four or more kinds of elements. Such silicate phosphors are good candidates for PLD studies.

In the past, PLD has been employed for the growth of phosphor thin films such as ZnS, SrS, ZnO, YAGG, Y_2O_3 :Eu [5-9]. It has not been applied to silicate phorsphors. RE-doped yttrium silicate phosphor has also been deposited by sputtering [10]. In here, we report our work of PLD deposited RGB silicate phosphors doped with different transition and rare-earth

metals in their thin film form. We shall also correlate their structural, surface morphology to the luminescent properties.

Experimental

Commercial phosphor powders from Phosphor Technology (CaSiO₃:MnPb, Zn₂SiO₄:Mn, Y_2 SiO₅:Ce) were cold-pressed into 1"-disks, and sintered at 1000°C for 5 hours to make hard ceramic targets for laser ablation. The pulsed laser deposition experiments were performed on these targets with a 193nm Lambda Physik ArF excimer laser. The substrates used for the deposition were either (100) bare silicon or silicon substrates with a thermally grown 1000A silicon dioxide on top.

All the films were deposited at a substrate temperature of 300°C. Annealing were performed on these samples in air at temperatures ranging from 400°C to 1200°C. All as-grown and annealed films were characterized by X-ray photoelectron spectroscopy (XPS), X-ray diffraction (XRD), scanning electron microscopy (SEM), atomic force microscopy (AFM), and photoluminescence (PL) measurements.

Results and discussion

Table 1. Chemical composition (%) of $CaSiO_3:MnPb$ target, as-grown and $1000^{\circ}C$ annealed films.

	С	0	Si	Ca	Mn	Pb
target	2.68	60.56	21.72	13.21	1.60	0.23
as-grown	3.07	60.13	20.16	14.85	1.78	0.02
1000°C	2.31	58.88	20.26	16.84	1.69	0.02

The phosphor films were generally 300nm to 400nm thick as calibrated by a profiler. The XPS results showed that for all three kinds of phosphors, there is no change of the chemical state, and minor change of chemical composition for the target, the as grown and 1000° C annealed samples. Using



Fig 1. XRD 2θ - θ scan of as-grown, 800° C and 1000° C annealed Zn₂SiO₄:Mn, Y₂SiO₅:Ce, and CaSiO₃:MnPb films on SiO₂/Si respectively (from top down).

CaSiO₃:MnPb as an example, the elemental concentrations were shown in Table 1. It can be seen that although the concentration of Ca, Si and O deviate

Fig 2. Relative PL intensity of Zn_2SiO_4 :Mn, Y_2SiO_5 :Ce, and $CaSiO_3$:MnPb thin film as a function of annealing temperature respectively from top down.

from that of stoichiometric CaSiO₃, which is acceptable for such a complex system, all the elements were well preserved as the target except Pb.



Fig 3 SEM pictures of (from right to left) as grown, 800° C and 1000° C annealed Zn₂SiO₄:Mn, Y₂SiO₅:Ce and CaSiO₃:MnPb (from top down) phosphor films respectively.

The XRD θ -2 θ scans are shown in Fig 1 for the as-grown, 800°C and 1000°C (5 hours in air) annealed Zn₂SiO₄:Mn, Y₂SiO₅:Ce, and CaSiO₃:MnPb films grown on SiO₂/Si. Increasing crystallinity is clearly seen with increasing annealing temperature.

The PL intensity versus annealing temperature was depicted in Fig 2 for silicate phosphor thin films grown on SiO₂/Si as a function of annealing temperature. There is no improvement of using bare Si substrate over SiO₂/Si in terms of crystallinity from the XRD data. The as-grown and low temperature annealed Zn₂SiO₄:Mn and CaSiO₃:MnPb films showed no photoluminescence. The as-grown Y_2SiO_5 :Ce film showed a weak photoluminescence. With post-annealing at a temperature of 700°C or higher for 5 hours in air, the luminescent property improved significantly.

From Fig. 2, it can be seen that the photoluminescence of the annealed sample showed

increasing PL intensity with annealing temperature from 800° C to 1000° C, the PL intensity tends to saturate with further increase of the annealing temperature. The enhanced luminescence correlates well with the increasing crystallinity at increasing annealing temperature. The phosphor films deposited on Si substrate and SiO₂/Si substrate showed comparable PL intensity after annealed, indicating that the luminescence is not sensitive to the substrate used.

SEM pictures of the samples are shown in Fig 3. The surface morphology of the phosphor films grown on SiO_2/Si substrate resembles that of the film grown on Si. Note that the cracks on the SEM picture of the asgrown $CaSiO_3$:MnPb sample is due to electron



Fig 4 PL spectra of red $CaSiO_3:MnPb$, green $Zn_2SiO_4:Mn$ and blue $Y_2SiO_5:Ce$ phosphor films grown by PLD.

beam induced peeling during SEM photographing. Combining the AFM data (not shown here) with the SEM results, it is inferred that the surface morphology does not change much with lower annealing temperature ($< 800^{\circ}$ C). However, with annealing temperatures higher than 800° C, the surface becomes a little bit rough. The PL intensity as shown by Fig 2, experiences a sharp change at about 800° C for all three kinds of phosphors. So the enhanced luminescence is due to the increased crystallinity as well as better surface morphology. But the PL intensity, the film crystallinity and surface morphology are not sensitive to the substrate used.

Reasonably good purity RGB chromaticity is obtained from the CaSiO₃:MnPb, Zn₂SiO₄:Mn, and Y_2SiO_5 :Ce films. Fig 4 shows the spectra measured with a Photo Research (model PR650) spectrometer. The PL of the CaSiO₃:MnPb, Zn₂SiO₄:Mn, Y_2SiO_5 :Ce films peak at 620nm, 520nm and 400nm respectively. The red tail of Zn₂SiO₄:Mn (green) and Y_2SiO_5 :Ce (blue) phorsphors come from the unfiltered light of the xenon lamp excitation source. The red emission spectrum of CaSiO₃:MnPb thin film was measured with 193nm ArF laser excitation. The corresponding CIE chart is shown in Fig. 5.

Conclusions

In summary, RGB silicate phosphor thin films on both Si and SiO₂/Si substrates were fabricated by pulsed laser deposition. Films deposited at 300°C substrate temperature showed no photoluminescence. Subsequent annealing at 800°C-1000°C in air produced



Fig 5 Chromaticity coordinates of the red CaSiO₃:MnPb, green Zn₂SiO₄:Mn and blue Y₂SiO₅:Ce phosphor films grown by PLD.

strong red, green and blue photoluminescence for all three colors. It is expected that these silicate phosphor thin films should have applications in low voltage cathodoluminescence for field emission displays and in electroluminescence displays.

References

- 1. P. N. Yocom, J. of SID 4, 149 (1996).
- T Minani, T Miyata, S Takata, and I Fududa, Jap. J Appl. Phys. 30, L117 (1990).
- 3. J. M. Robertson, Thin Solid Films 141, 221 (1984).
- D. B. Chrisey, and G. K. Hubler, <u>Pulsed Laser</u> <u>Deposition of Thin Films</u>, John Wiley & Sons, Inc. (1994).
- M. McLaughlin, H. Sakeck, P. Macquire, W. Graham, J. Molloy, T. Morrow, S. Lavery, and J. Anderson, Appl. Phys. Lett. 63, 1865 (1993).
- C. Karner, P. Maguire, J. McLaughlin, S. Laverty, W. G. Graham, T. Morrow, R. M. Bowman, Philosophical Magazine Letters **76**, 111 (1997).
- J. M. Siqueiros, J. A. Diaz, O. Contreras, G. A. Hirata, and J. McKittrick, Mater. Res. Soc. Symp. Proc. **397**, 247 (1996).
- J. Greer, H. Van Hook, M. Tabat, H. Nguyen, G. Gammie, and P. Koufopouls, Mater. Res. Soc. Symp. Proc. 345, 281 (1994).
- 9. S. L. Jones, D. Kumar, R. K. Singh, and P. H. Holloway, Appl. Phys. Lett. **71**, 404 (1997).
- X. Ouyang, A. H. Kitai, R. Siegele, Thin Solid Film 254, 268 (1995).